

10/089621
 JCTO R PCT/PTO 01 APR 2002

U.S. DEPARTMENT OF COMMERCE
 PATENT AND TRADEMARK OFFICE

INFORMATION DISCLOSURE STATEMENT

Docket Number
10191/2287

Application Number
 To Be Assigned

Filing Date
 Herewith

Examiner
 To Be Assigned

Art Unit
 To Be Assigned

Invention Title
**INTERFEROMETRIC MEASURING DEVICE
 FOR MEASURING SHAPE**

Inventor(s)
Michael LINDNER et al.

Assistant Commissioner
 for Patents
 Washington, D.C. 20231

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following references (cited in the specification of the above-identified application) to the attention of the Examiner. The references are listed on the attached modified PTO Form No. 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

Dated: 4/1/02

By: for Richard L. Mayer
 Richard L. Mayer (Reg. No. 22,490) (by)

KENYON & KENYON
 One Broadway
 New York, N.Y. 10004
 (212) 425-7200 (telephone)
 (212) 425-5288 (facsimile)

36,197
 Rj. No.

EL 327553862US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT PTO FORM 1449

 Atty. Docket No.
10191/2287

 Serial No.
To Be Assigned

 Applicant(s)
Michael LINDNER et al.

 Filing Date
Herewith

 Group
To Be Assigned

U. S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,933,237*	August 3, 1999	Drabarek			
	5,493,398*	February 20, 1996	Pfister			
	5,155,363*	October 13, 1992	Steinbichler et al.			
	3,849,003*	November 19, 1974	Velzel			

*Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority, and relevance noted in Search Report, copy of which is enclosed herewith).

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
						YES	NO
	197 21 842**	December 3, 1998	DE				
	41 08 944**	September 24, 1992	DE				
	WQ 92 19930*	November 12, 1992	PCT				
	03 120436*	May 22, 1991	JP				
	196 25 830*	January 2, 1998	DE				
	197 21 843**	February 11, 1999	DE				

*Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority, and relevance noted in Search Report, copy of which is enclosed herewith).

** Described in Specification.

OTHER DOCUMENTS

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	Patent Abstracts of Japan, vol. 015, no. 327 (P-1240), (August 20, 1991).*
	P. de Groot, L. Deck, "Surface Profiling by Analysis of White-Light Interferograms in the Spatial Frequency Domain" J. Mod. Opt., Vol. 42, No. 2, 389-401, (1995).*
	No. T. Maack, G. Nomi, W. Schreiber, W.-D. Prenzel, "Endoscopic 3-D Shape Measuring System", Jahrbuch fur Optik und Feinmechanik, Ed. W.-D. Prenzel, 231-240, (1998)**

*Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority, and relevance noted in Search Report, copy of which is enclosed herewith).

** Described in Specification.

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609, draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	